



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2829
Examiner: J. Hollington

4-17-03
J. Hollington

In Re PATENT APPLICATION OF:

Applicant: Mikio OHTAKI

Appln. No.: 09/904,663

Filed: July 16, 2001

For: METHOD FOR MANUFACTURING
AND BATCH TESTING
SEMICONDUCTOR DEVICES
(As Amended)

Atty Ref.: KAN 120D1

INFORMATION DISCLOSURE
STATEMENT

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Commissioner for Patents
Washington, D.C. 20231

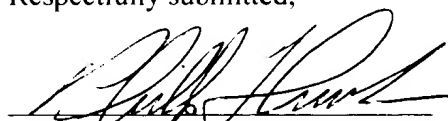
Sir:

This is an information disclosure statement submitted in compliance with the timing requirements of 37 C.F.R. §1.97(c), i.e., after a first Office Action on the merits but before Notice of Allowance. Pursuant to 37 C.F.R. § 1.97(e)(2), it is certified that each item submitted with this Information Disclosure Statement was cited in an Office Action from the Japanese Patent Office in a counterpart foreign application on January 10, 2003, that is, less than three months prior to filing this Information Disclosure Statement.

Attached are copies of the Japanese Patent Abstracts cited therein and the two US Patents. The relevance of the Japanese publication can be gleaned from the attached English language Abstract. The documents are listed on the attached Form PTO-1449.

Consideration of the submitted documents is respectfully requested.

Respectfully submitted,


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April 10, 2003
Date

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